

ABSTRACT

In a discharge processing method wherein an insulating processing medium (13) is interpolated between an electrode (1) and a processing subject (2) and discharging energy is supplied between the electrode (1) and the processing subject (2) so that the processing subject (2) is processed by the discharge, a processing is carried out with the electrode (1) being pressed onto the processing subject (2) at a predetermined pressure so as to allow the processing medium (13) between the electrode (1) and the processing subject (2) to form a thin film while the electrode (1) and the processing subject (2) are being relatively moved.